THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No
Filing Date March 17, 2004
nventorWarren M. Farnworth et al.
AssigneeMicron Technology, Inc.
Group Art Unit2829
Examiner Russell Marc Kobert
Attorney's Docket NoMl22-2524
Title: Method and Apparatus for Testing Semiconductor Circuitry for Operability and
Method of Forming Apparatus for Testing Semiconductor Circuitry for Operability

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Reference - - See attached Form PTO-1449

The attached Form PTO-1449 is submitted in compliance with 37 C.F.R. §§ 1.56. Pursuant to Federal Register Vol. 69, No. 182, pg. 56542 (September 21, 2004), no copies of any cited U.S. patents or U.S. published applications are included herewith. No admission is made regarding whether the submitted reference is prior art.

Citation of this reference is respectfully requested.

Respectfully submitted,

Date: 11-14-05

D. Brent Kenady Reg. No. 40,045 Customer No. 021567

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Form PTO-1449

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ATTY. DOCKET NO. MI22-2524

SERIAL NO. 10/803,264

APPLICANT

Warren M. Farnworth et al.

FILING DATE March 17, 2004

GROUP 2829

LLS PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Name	Class	Subclass	Filin If App	ng Date propriate
	AA	6,686,758	02/04	Farnworth et al.	324	765		
	AB	5,201,992	04/93	Marcus	216	11		
	AC							
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	AE							
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	AJ							
			FOREI	GN PATENT DOCUMENTS	S			
		Document Number	Date	Country	Class	Subclass	Transla Yes	tion No
	AK						103	140
	AL							
	AM							
		OTHER REF	ERENCES (in	acluding Author, Title, Date, F	ertinent Page	s, Etc.)		
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.